

FORM HDP-1449 (Based on Form PTO-1449)		ATTORNEY DOCKET NO.	SERIAL NO.
PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)		7784-000107/DVA	N/A
Sheet 1 of 2		APPLICANT	
		Blackmon et al.	
		FILING DATE	GROUP
		N/A	N/A

U.S. PATENT DOCUMENTS						
Ref. Desig.	Examiner's Initials	Document Number	Date	Name	Class/ Subclass	(If appropriate) Filing Date
1.	RSH	3,456,134	07/15/1969	Ko		
2.		3,466,473	09/09/1969	Rhoten		
3.		3,553,588	01/05/1971	Honig		
4.		3,624,451	11/30/1971	Gauld		
5.		4,467,236	08/21/1984	Kolm et al.		
6.		4,510,484	04/09/1985	Snyder		
7.		5,463,374	10/31/1995	Mendez et al.		
8.		5,632,841	05/27/1997	Hellbaum et al.		
9.		5,751,091	05/12/1998	Takahashi et al.		
10.		5,801,475	09/01/1998	Kimura		
11.		5,849,125	12/15/1998	Clark		
12.		6,162,313	12/19/2000	Bansemir et al.		
13.		6,306,773	10/23/2001	Adas et al.		
14.		6,382,026	05/07/2002	Tajika et al.		
15.		6,407,484	06/18/2002	Oliver et al.		
16.	↓	6,530,276	03/11/2003	Tajika et al.		

FOREIGN PATENT DOCUMENTS						
Ref. Desig.	Examiner's Initials	Document Number	Date	Country	Class/ Subclass	Translation Yes No
1.	RSH	GB 2 026 284	04/17/1978	United Kingdom		
2.	↓	GB 2 064 883	11/27/1979	United Kingdom		

Examiner: *Ronald S. Head* Date Considered: *10/15/05*

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Sheet 2 of 2			

OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, etc.)		
Ref. Desig.	Examiner's Initials	
1.	<i>PSH</i>	Ibong Jung and Yongrae Roh, Design and fabrication of pieoceramic bimorph vibration sensors, Sensors and Actuators A69 (1998) 259-266.
2.		F.J. von Preissig and E.S. Kim, Topics in Finite-Element Modeling of Piezoelectric MEMS.
3.		Meteer, Jami, Front-Side Processign of a Piezoelectric MEMS Accelerometer, The Pennsylvania State University National Nanofabrication Users Network, pp. 48-49
4.		Kloeppe, James E., Residual stress in piezoelectric ceramics can be reduced, put to work, News Bureau, (Sept. 1, 2000).
5.		Face International Corporation, Thunder White Paper (Feb. 21, 2001).
6.		Physics and Media Group, Parasitic Power Harvesting in Shoes (Aug. 1998).
7.		USSN 10/274,577, filed 10/21/2002, entitled: "Multi-Frequency Piezoelectric Energy Harvester".
8.	<i>✓</i>	USSN 10/361,533, filed 02/10/2003, entitled " Single Crystal Piezo (SCP) Apparatus And Method of Forming Same".

Examiner: <i>Raymond Shabot</i>	Date Considered: <i>11/15/05</i>
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